

# From Lithography to Light Scaling Compute Beyond Shrink

Johannes Zellner  
Head of Roadmap Technology



2025-11-17



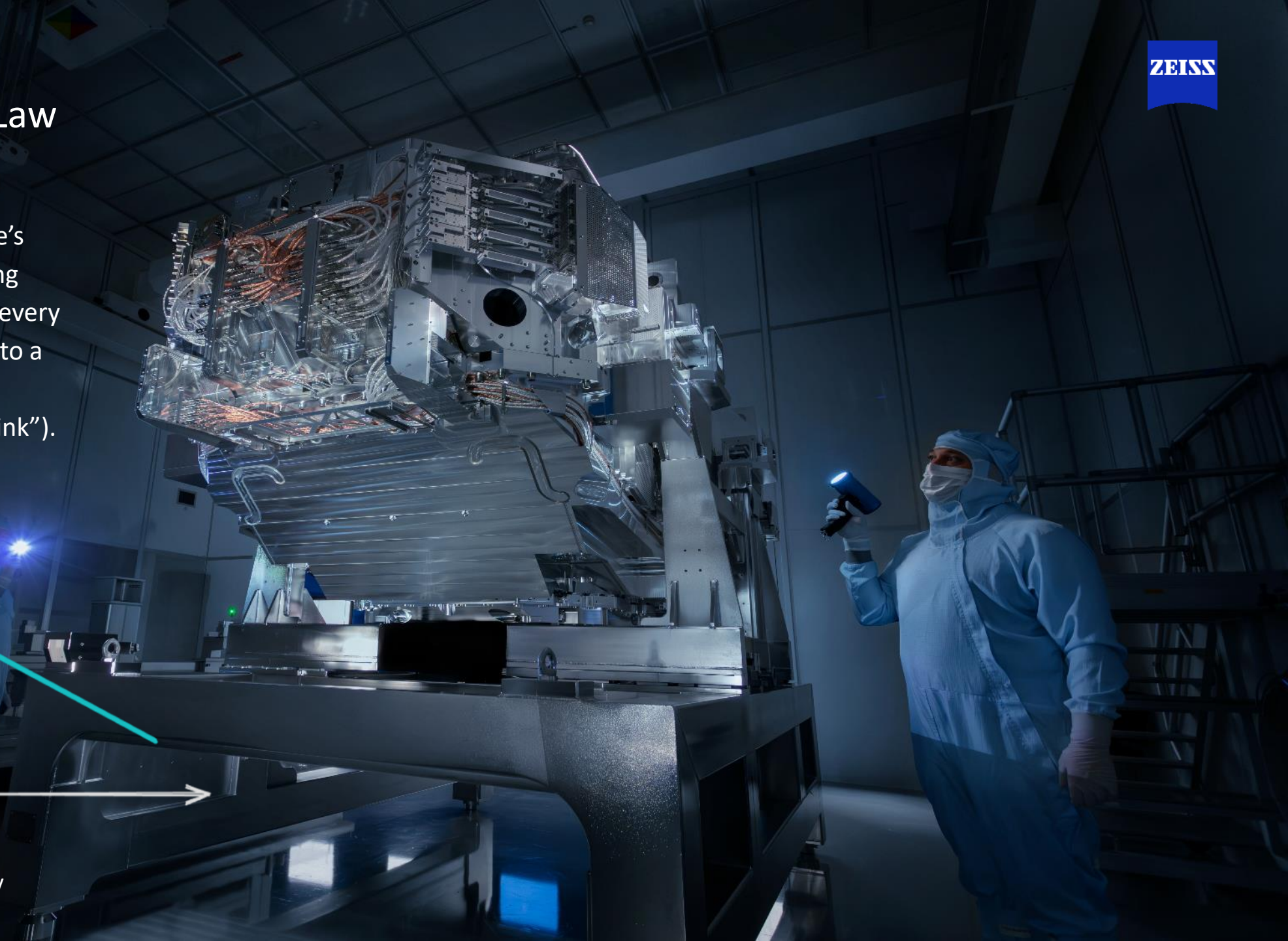


# Setting the Stage Enabling Moore's Law

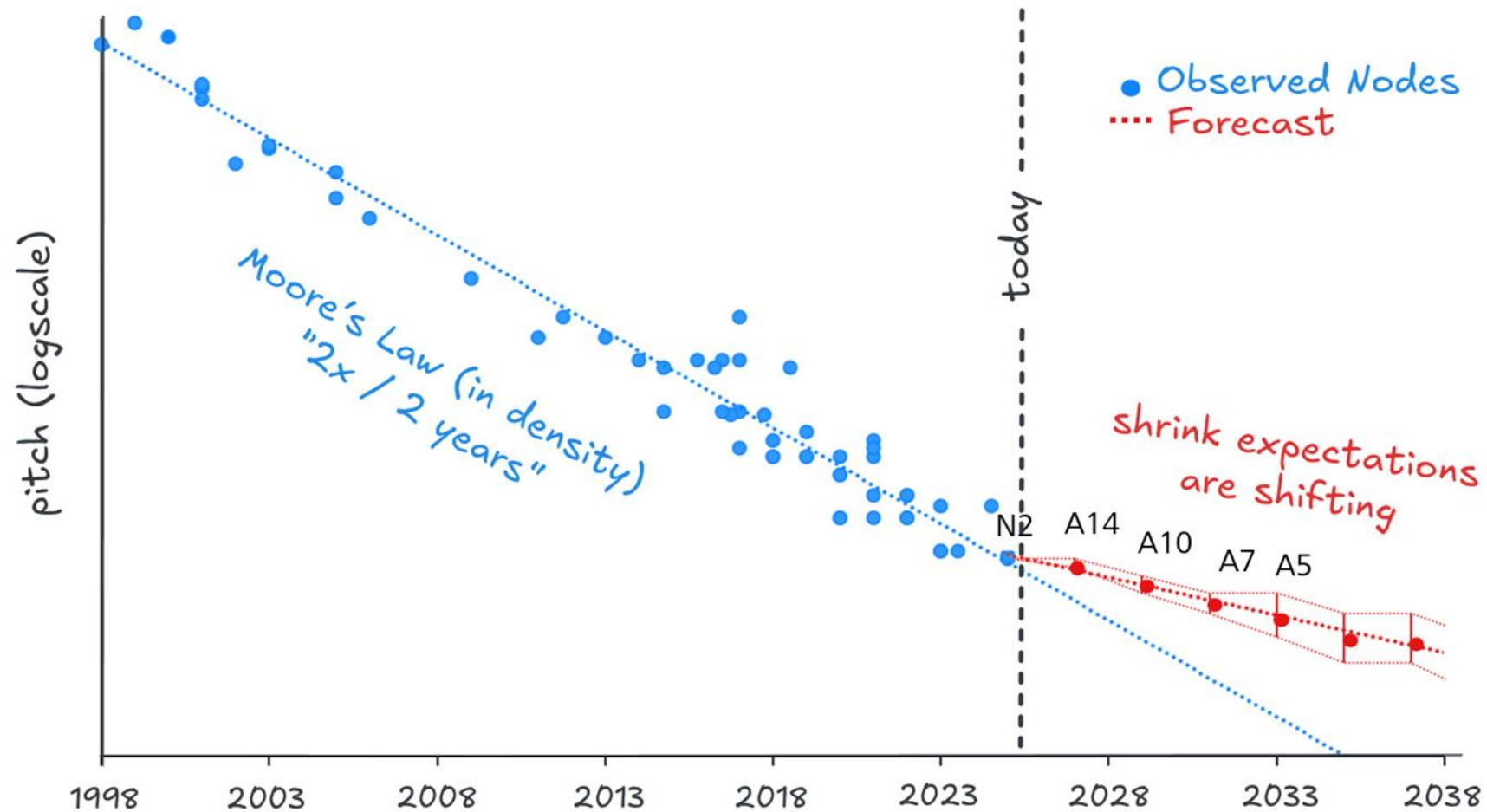
ZEISS SMT has driven Moore's Law\* for decades — enabling transistor counts to double every two years. This translates into a continuous **roadmap** for feature-size reduction (“shrink”).



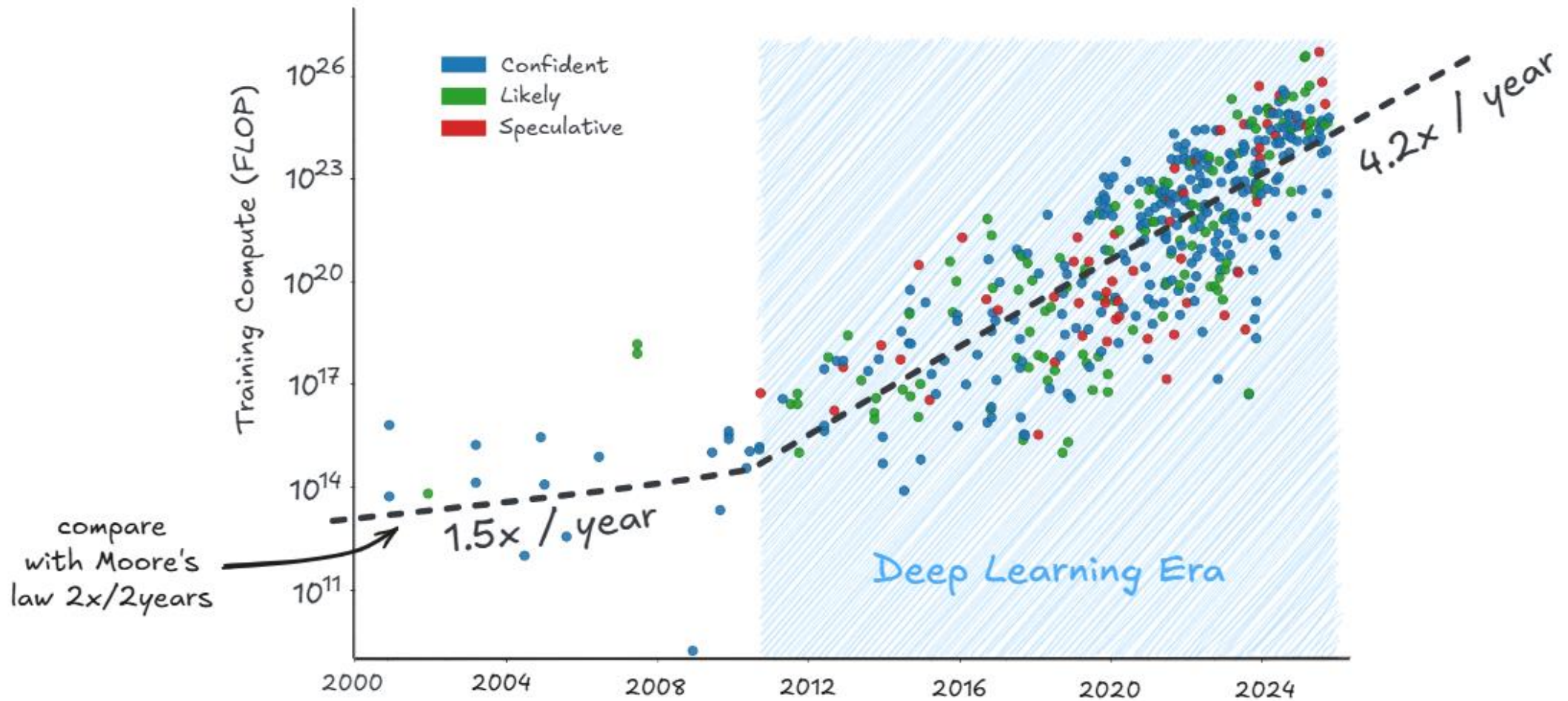
\*rather a self-fulfilling prophecy



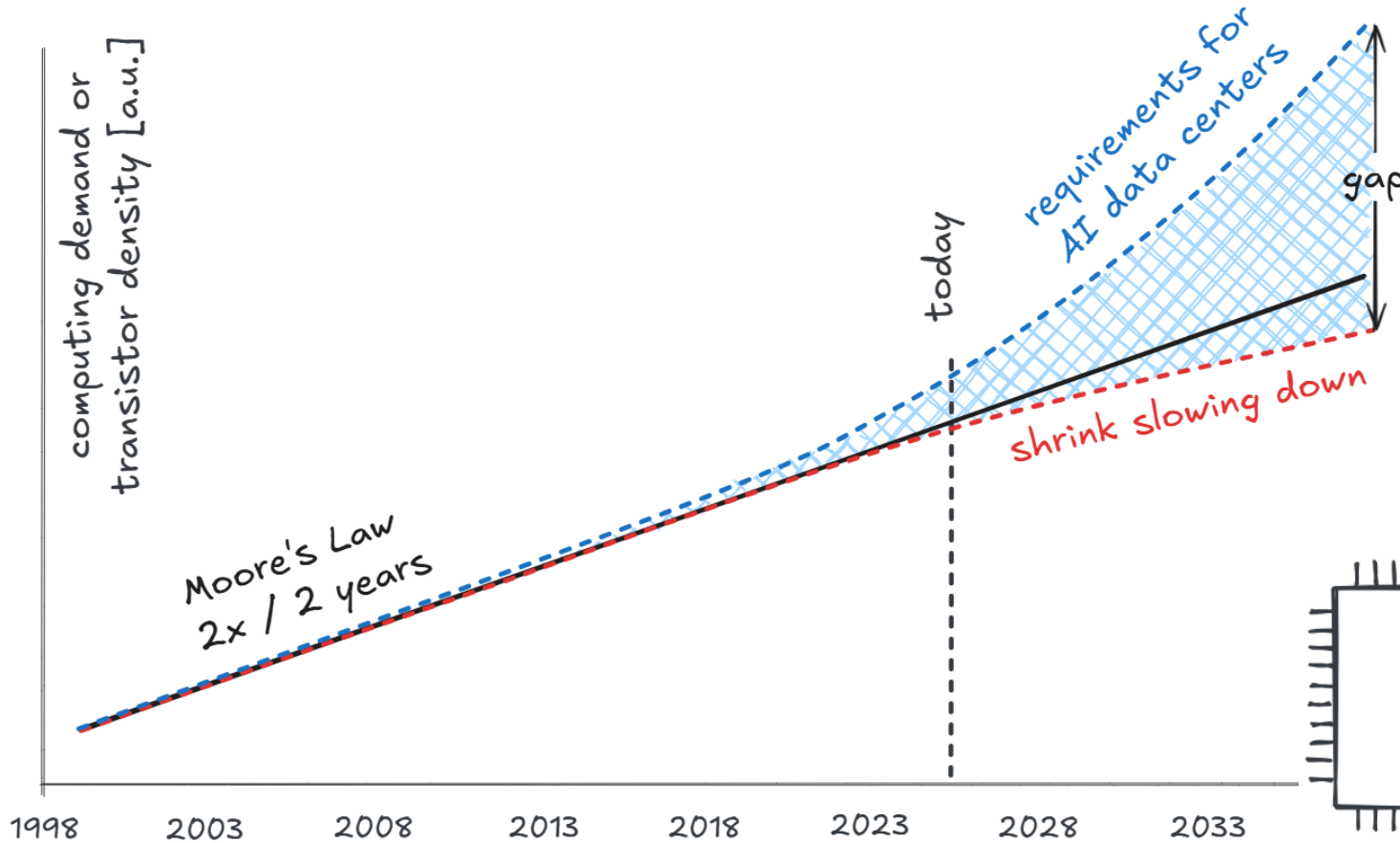
However dimensional shrink is slowing down ...  
 ... do we start to hit the limits of exponential growth?



# On the horizon a massive demand for powering AI chips ... ... and it's not only about training.

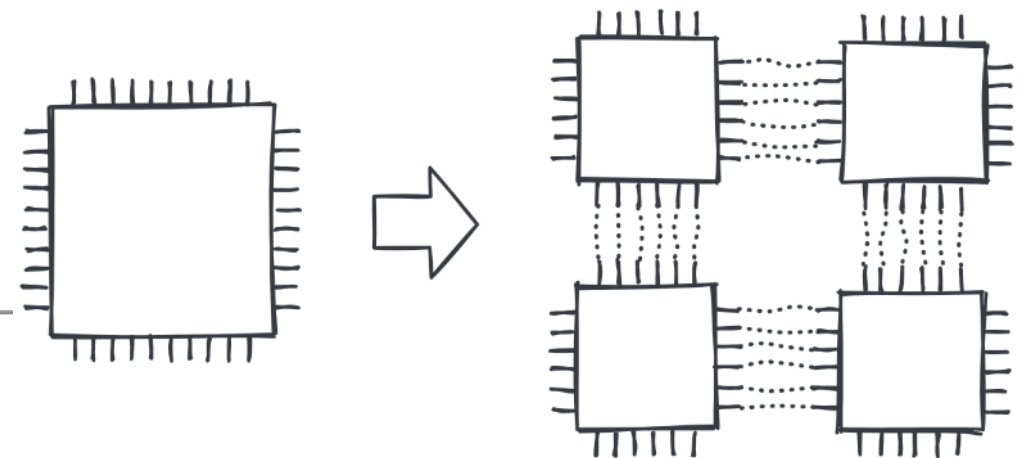


# A two-fold challenge: exploding AI demand & slowing shrink → heterogeneous integration / advanced packaging



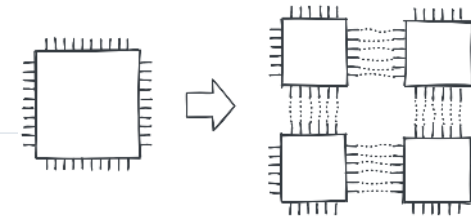
- There's an increasing two-fold performance gap
1. exponentially growing demand for AI which by far outpaces Moore's law.
  2. traditional dimensional shrink-based improvements are slowing down.

→ we need scale beyond shrink.



# scaling beyond Moore's Law ...

## ... implications of heterogeneous integration



AI Computing is fundamentally a data management task.  
The gap widens between processing and datacom BW.

**Chiplet integration** with advanced packaging demands ultra-fast, energy-efficient communication.

### Limits of Electrical Links:

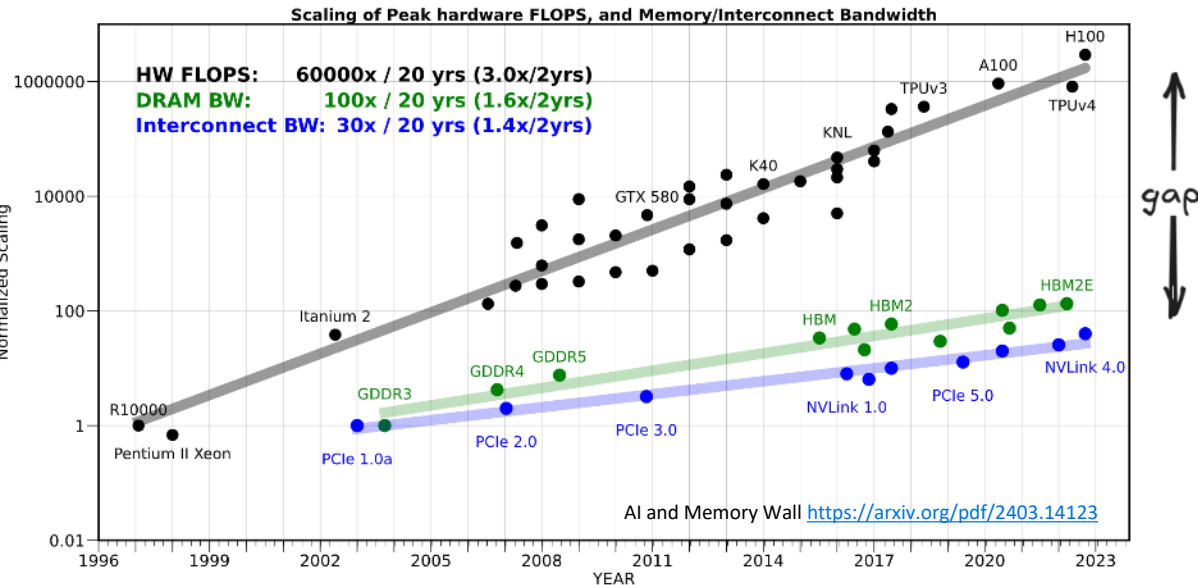
- **Bandwidth bottleneck** (+ “beachfront-limited”):
- **High energy per bit** → scaling increases power and heat.

### Photonic Links Advantage:

- **Massively higher bandwidth**
- **Significantly lower energy per bit**

Switching from pluggables to CPO cuts energy use by ~4x.

→ Only photonics can deliver the speed and power efficiency needed for next-gen AI and HPC systems.



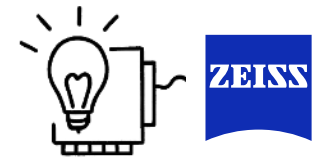
recap: demand for AI training grows 4.2x/year

# From Moore's Law to More Ways: scaling compute for AI

## A cross-technology plan — lithography, packaging and photonics



# From Moore's Law to More Ways: scaling compute for AI Ambition, scope and approach with on-package optical I/O.



We prepare technology for ZEISS as an *equipment provider* for on-package optical I/O.

## Guiding Principles

### Material & Platform Agnostic

Flexible approach across technologies.

### Leverage Existing ZEISS Capabilities

Accelerate development for HVM solutions by building on proven technology and stages.

### Manufacturing Technology

Deliver robust solutions for high-volume production.

### Metrology & Functional Testing

Ensure precision and performance at scale.

### Assembly Support

Facilitate seamless integration into customer workflows.

## Scope

1. *Co-packaged optics*

2. *chiplet communication on large photonic interposers*

## Approach

**Leverage lithography relationships** with leading customers to capture requirements and gain insight into photonics roadmaps.

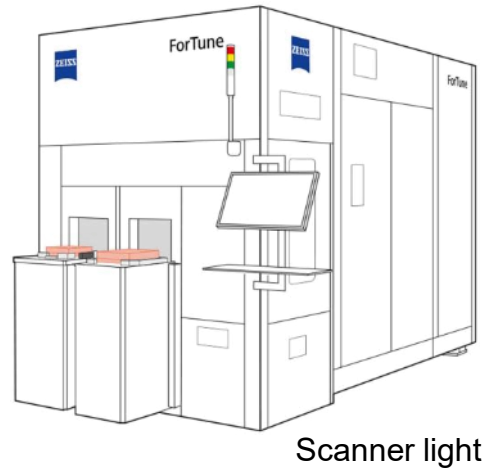
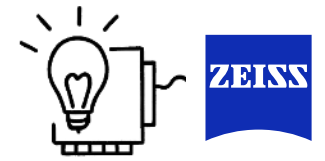
**Actively partner** with other companies across the value chain to combine strengths, create synergies, and drive innovation.

**Collaborate with R&D partners** through joint projects to accelerate technology understanding.

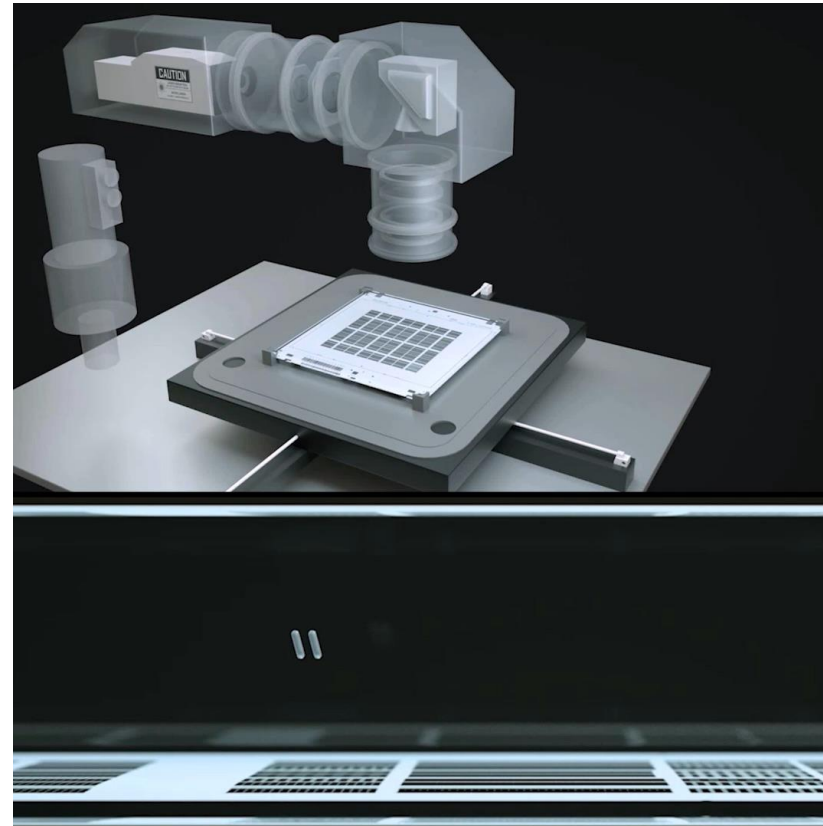
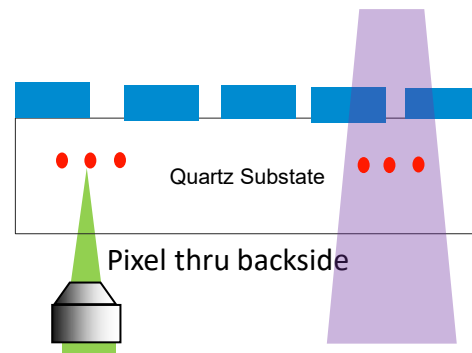
**Develop demonstrators and prototypes** to enable rapid feedback from customers and partners – “fail fast”.

# 3D waveguide writing – detour – photomask tuning ...

## ... enabling laser direct write beyond photomasks



Scanner light

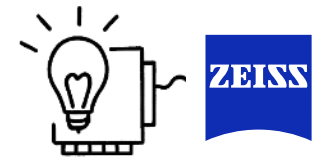


- The ZEISS ForTune System generates pixels in substrates to improve critical-dimension-uniformity (CDU) and overlay by using ultrashort laser pulses
- Well established technology for 15+ years
- installed base at mask shops and wafer fabs of major device makers (memory and logic)

- overlay control
- CDU Control

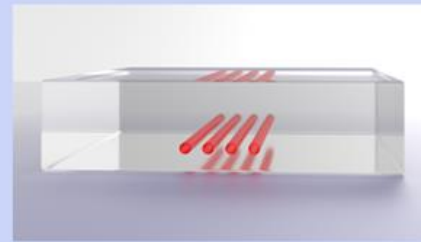
# 3D waveguide writing – retrofitted mask-tuning platform

## Laser direct write enables precision 3D waveguide writing in glass

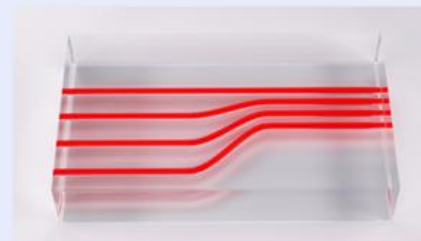


### LDW 3D waveguide writing

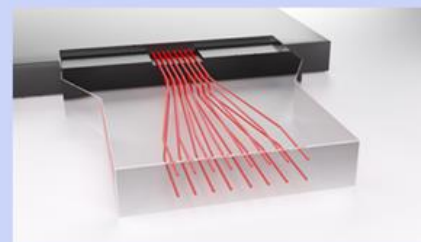
Straight WG



2D curved WG



3D WG

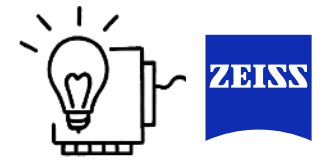


Industrial ZEISS platform with NIR wavelength ultra-short pulse laser adapted for waveguide laser direct writing (LDW) in glass proof-of-principle demonstration.

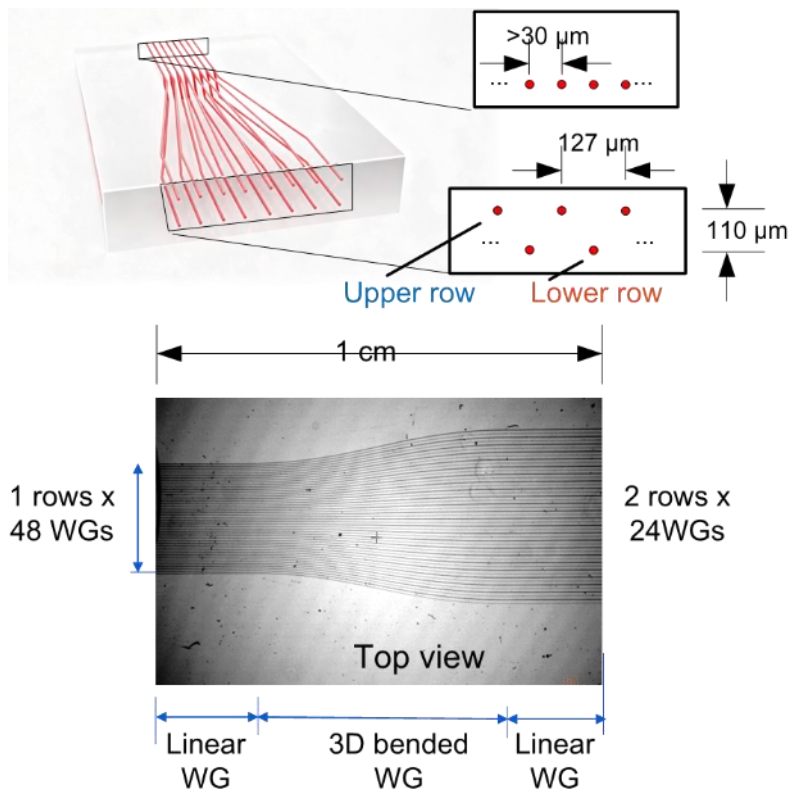
- Mode field diameter compatible to optical fibers
- Writing Speed → HVM ready

# 3D waveguide writing – proof of concept: 3D arrays

## Performance metrics

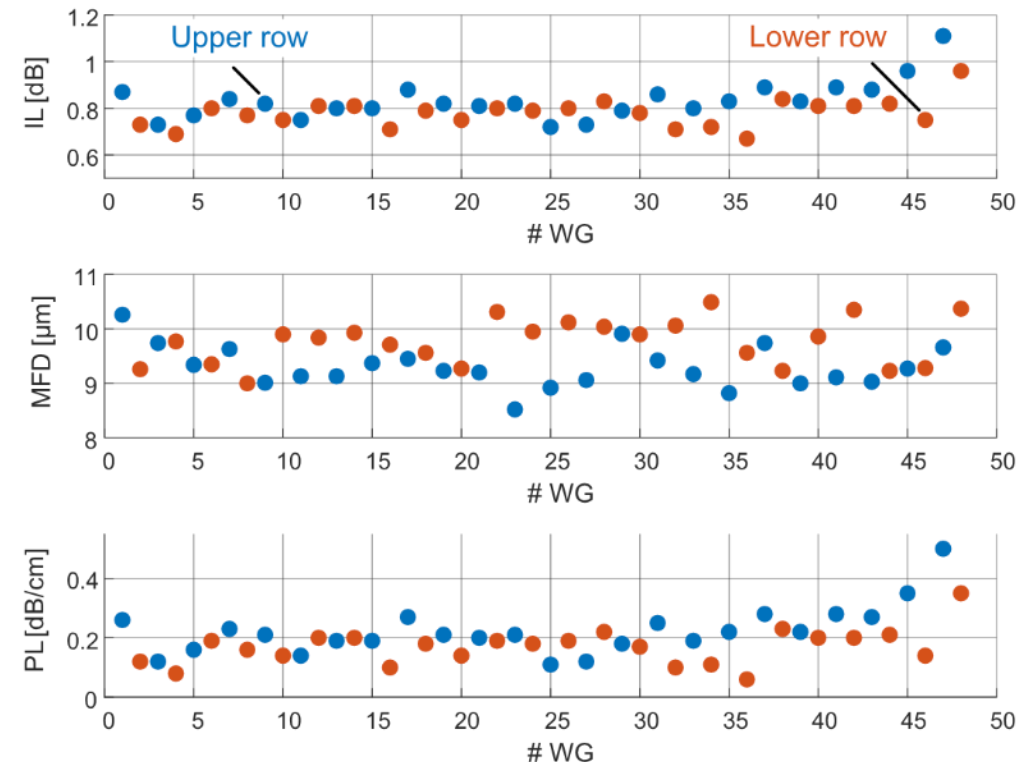


Schematic of 3D waveguides. On one side of the sample, the waveguides are arranged in one row. On the other side of the sample, a two-dimensional array is formed with a pitch of  $127\mu\text{m}$  and a vertical distance between the two rows of  $110\mu\text{m}$ .



Measurement results of all 48 waveguides.

- **Top:** insertion loss (IL) incl. free-space coupling loss
- **Middle:** mode-field diameter (MFD) of waveguide
- **Bottom:** estimated propagation loss (PL)



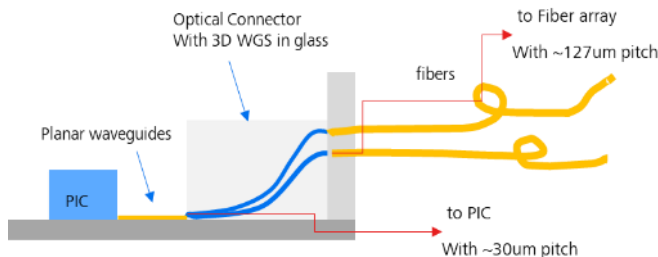
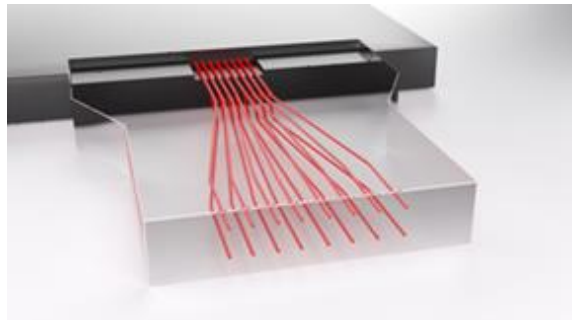
# 3D waveguide writing – scaling connectivity with light

## Optical connectors, glass interposers, TGV, and refractive-index tuning

### Optical Connector

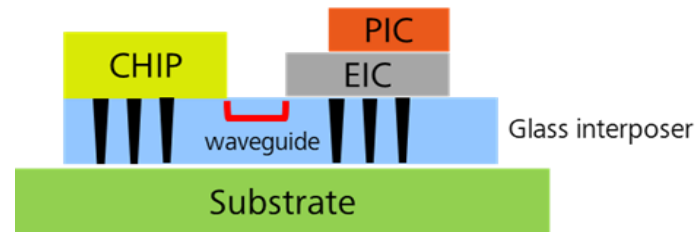
3D routing – reduce beachfront in Fiber to PIC Coupling.

Write waveguide on package to match exactly the (edge or grating) coupler.



### Glass interposers or panels

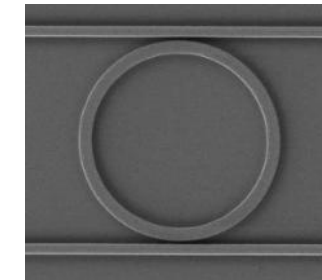
Waveguides in glass for optical connections including 3D routing.



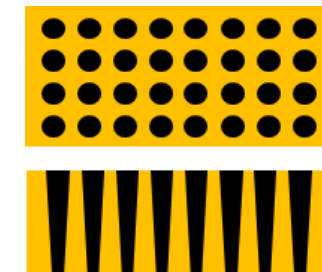
### Further applications

**Manipulate refractive index in glass or Si:**

→ tune / optimize / correct photonic structures

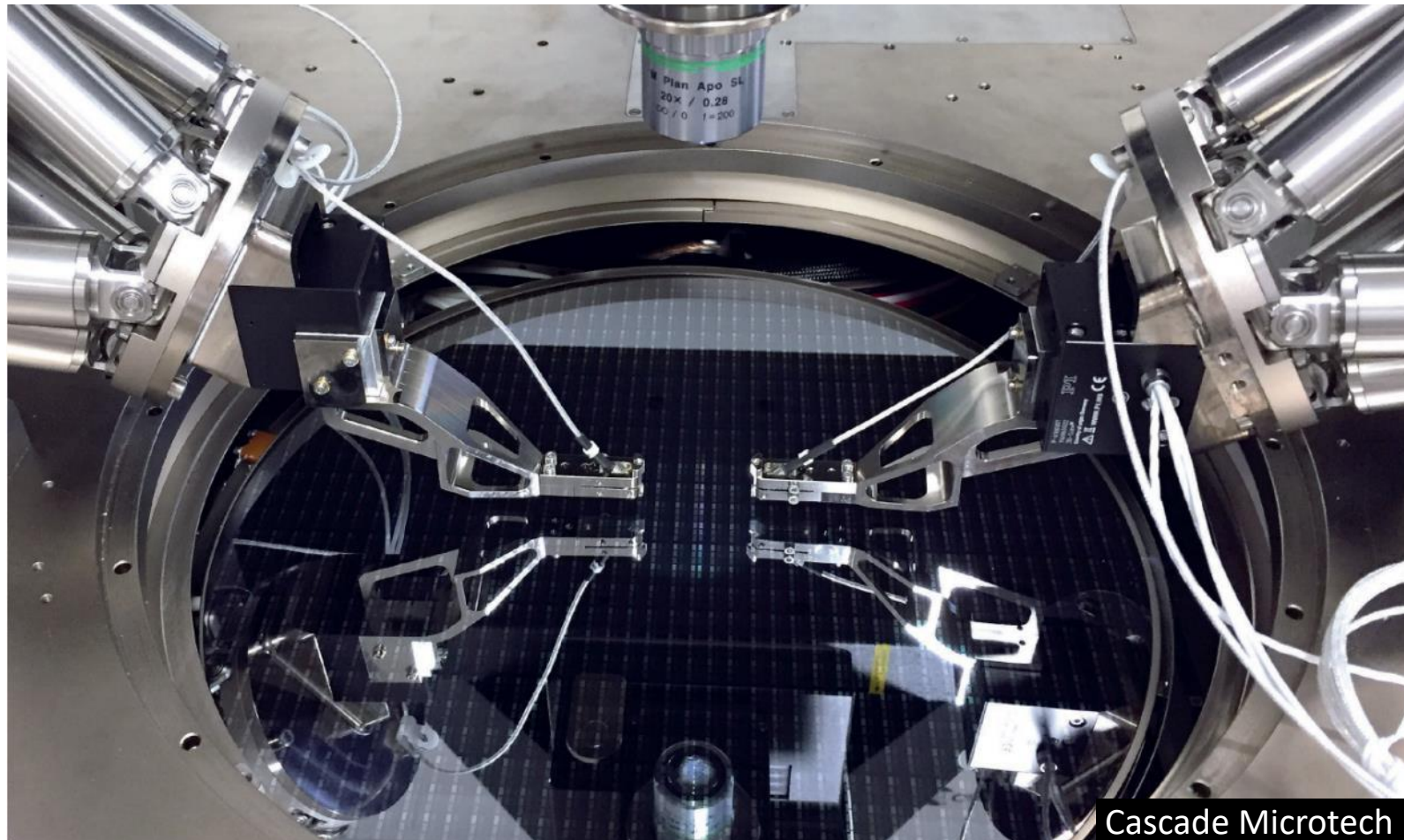
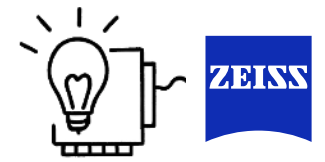


Through Glass Vias (TGV) by Laser Selective Etching



# PIC Testing

## State of the art functional testing



Injecting light into waveguides using fibers

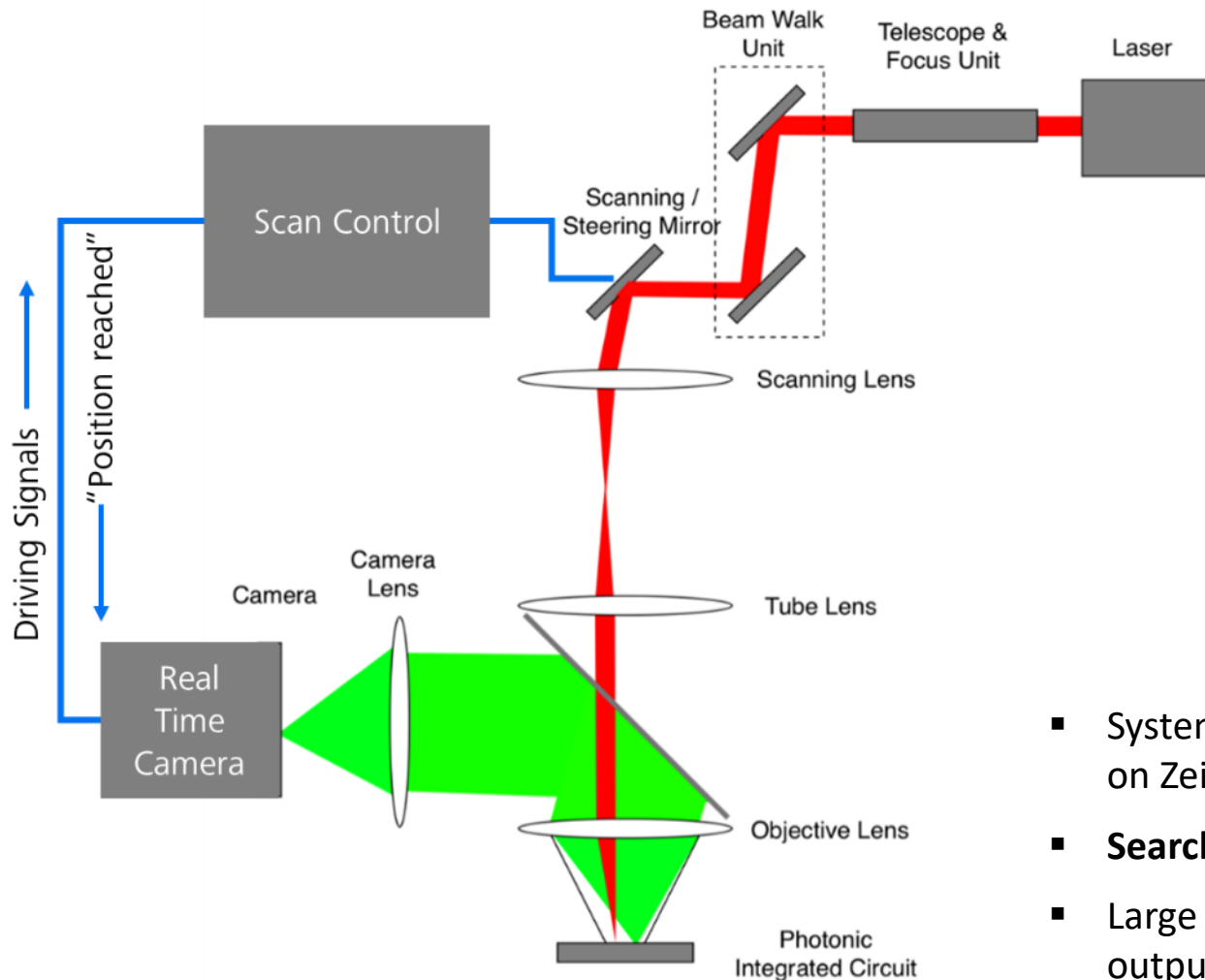
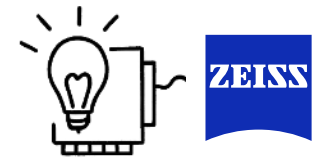
**Required Position Accuracy:**  
< 500 nm

**Fiber Alignment Speed:**  
Slow, ~ a few hundred milliseconds

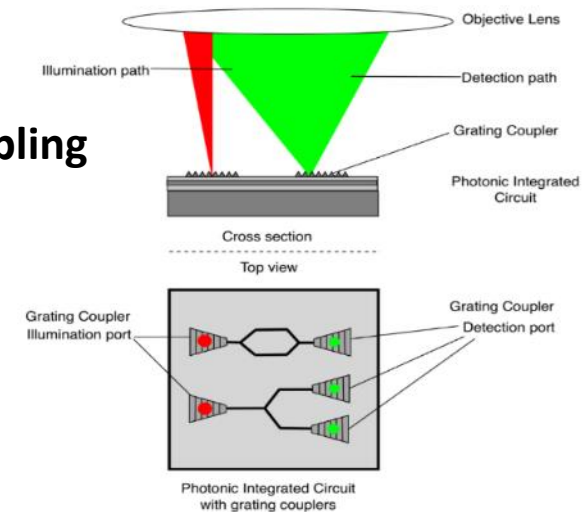
**Full Wafer Test Duration:**  
Several hours

# PIC Testing – high-throughput functional testing of PICs

## Ultra-fast free-space optical coupling

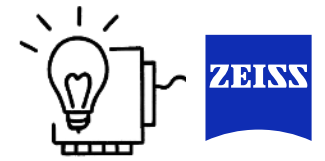


### Top Side Coupling



- System for functional testing of photonic integrated circuits based on Zeiss LSM microscopy systems
- **Search and coupling of light into PICs in ~ 10ms**
- Large working distance – can be combined with electrical input and outputs via e.g. probe cards

## PIC Testing – Status ... ... it's still a lab setup.



- Demonstrator set up including soft- & firmware for in-situ scan control and experimental validation
- Very encouraging feedback from several leading customers
- Customer test chips expected in the next weeks

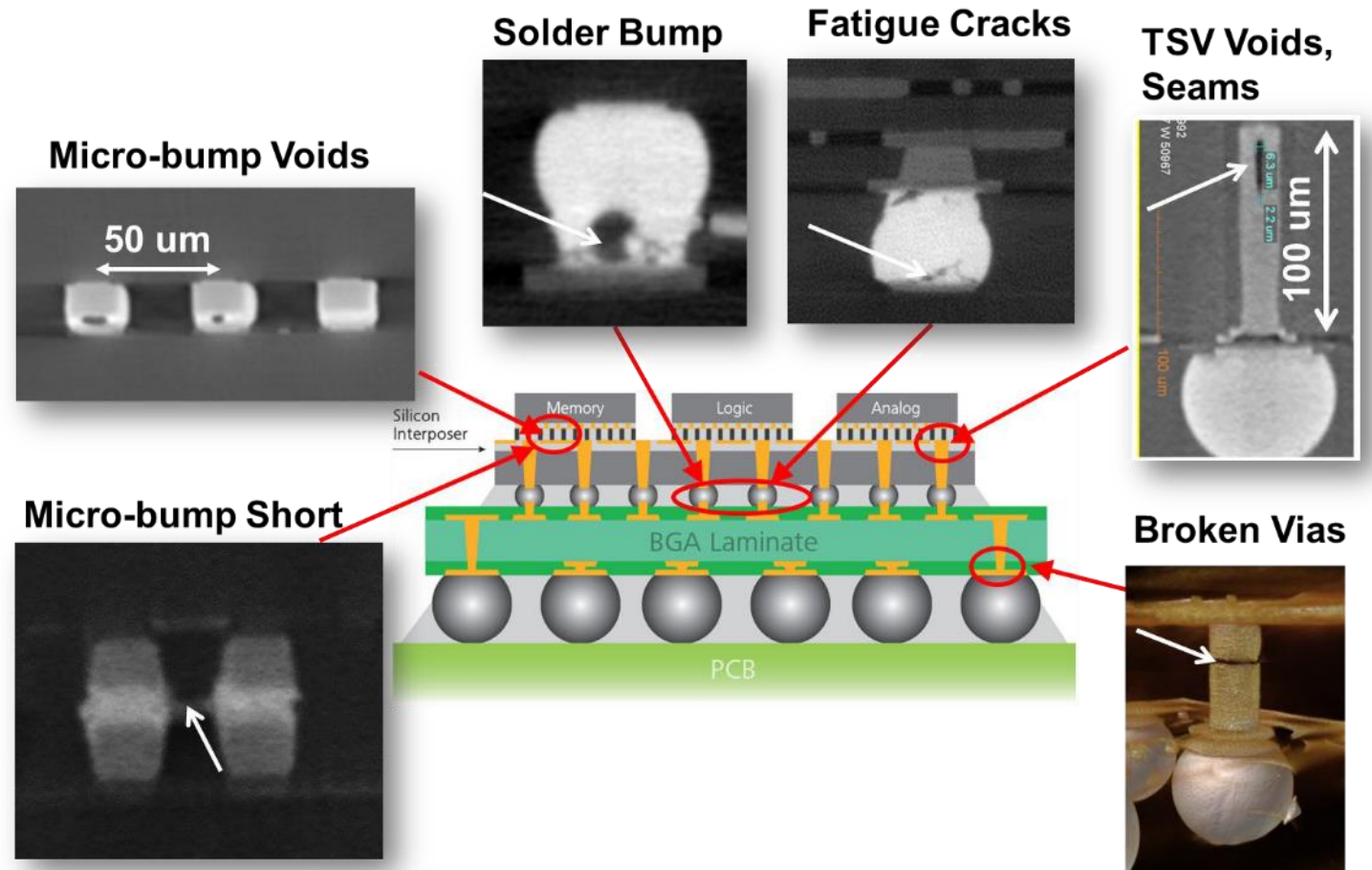
# 3D inline X-ray inspection – challenges in advanced packaging

Process-control calls for measuring and inspecting *inside* the package.



## Advanced 3D Integration

- Last-processed layer no longer on the surface
- Sub-10µm interconnect structures require more process control
- Ideally, non-destructive testing on many samples to detect, measure and counter-act on
  - Die-overlay
  - Cold-joints
  - Chip-gap and –tilt
  - Bridging
  - Missing bumps

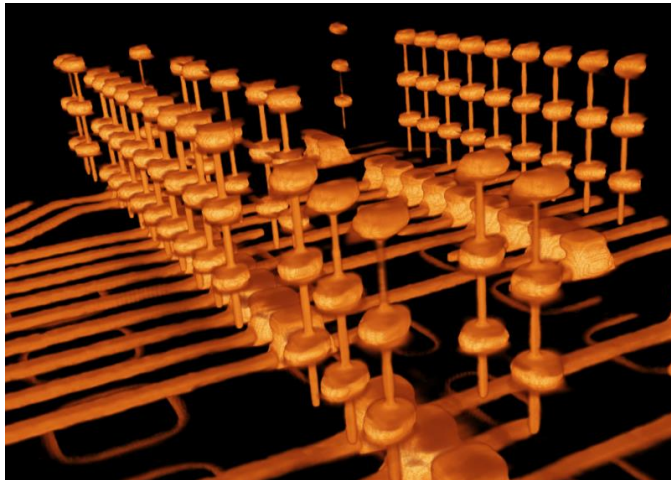


# 3D inline X-ray inspection – ZEISS NLX-100 system

A system designed for supporting semiconductor process control needs



- **Fully-automated X-ray system** for inline wafer inspection
- Consistent **high-quality 3D-imaging** across the wafer
- ZEISS X-ray source for **high throughput & high resolution**
- **Automated** data analytics
- **XGuard** shielding & dose control for protecting X-ray sensitive areas like HBM
- **Optical alignment** to minimize X-ray dose



## Beyond Shrink: New Scaling Paradigms and Scope

### Advanced Packaging & Photonics

**Co-packaged optics:** Key to scaling bandwidth, reducing energy, and latency.

**Large photonic interposers:** Enable heterogeneous integration (CPUs, GPUs, NPUs, HBM).

**ZEISS ambition:** Equipment for on-package optical I/O industry.



## Examples: Tech. Demonstrators

### 3D Waveguide Writing:

Laser direct-write for photonic integration in glass. Enables high-density, low-loss optical connections with 3D-routing.

### High-Throughput PIC Testing:

Free-space optical coupling for rapid, precise photonic chip testing.

### 3D Inline X-ray Inspection:

Automated, high-resolution process control for advanced packaging.

(further demonstrators for wafer warpage correction and particle removal are in the pipe)



## Approach

### Leverage customer relationships

... to capture requirements and gain insight into photonics roadmaps.

### Actively partner with companies

... across the value chain to combine strengths, create synergies, and drive innovation.

### Collaborate with R&D partners

... through joint projects to accelerate technology understanding.



Seeing beyond